

Application/Control No.	Applicant(s)/Patent under Reexamination		
10/566,840	IJPEIJ ET AL.		
Examiner	Art Unit		
Caixia Lu	1713		

SEARCHED									
Class	Subclass	Date	Examiner						
526	112 160	5/29/67	a						
	161*								
	165,PM	33							
	133								
	134								
502	155*								
	157								
	103								

INTERFERENCE SEARCHED									
Class	Subclass	Date	Examiner						
526	133,134	5/19/07	a						
	136,160		1						
	161,172								
502	155,157								
	183								

SEARCH NOTES (INCLUDING SEARCH STRATEGY)				
		DATE	EXMR	
				
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